

SPECIFICATION AMENDMENTS

1. Please amend the paragraph starting on page 1, line 3 as follows:

This invention relates to electromechanical systems and techniques for fabricating microelectromechanical and nanoelectromechanical systems; and more particularly, in one aspect, to fabricating or manufacturing for anchoring microelectromechanical and nanoelectromechanical devices to semiconductor on insulator ("SOI") substrates or the like.